



Alcatel ATP-400HPC, 900HPC

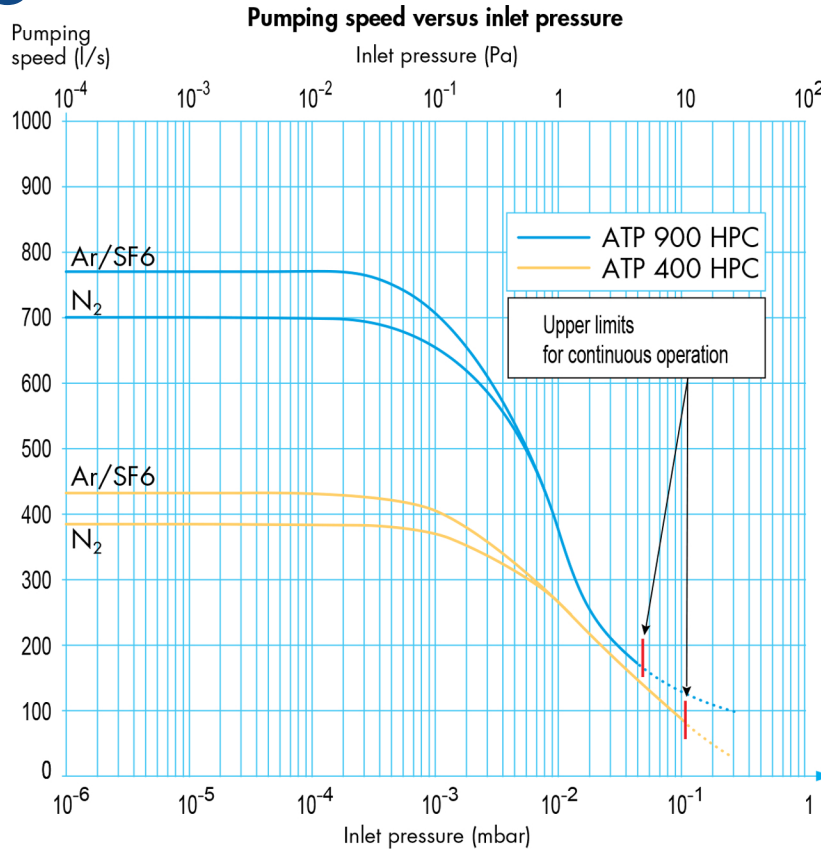
Technical Specifications

Characteristics		ATP 400 HPC		ATP 900 HPC	
Inlet flange		DN100 ISO-K	DN160 ISO-K	DN200 ISO-K	DN260 CF-F
Pumping speed	N ₂ l/s	325	380	700	
	Argon l/s	365	430	785	
	SF ₆ l/s	365	430	785	
Compression ratio	N ₂	7x10 ⁶		1x10 ⁷	
	Argon	700		2x10 ³	
	H ₂	100		200	
Ultimate pressure without purge (1)	mbar			5x10 ⁻⁸	
Ultimate pressure with purge (1)	mbar	8x10 ⁻⁶		5x10 ⁻⁵	
Purging nitrogen flow rate	sccm			50	
Maximum continuous inlet pressure	mbar	1x10 ⁻¹		1x10 ⁻²	
Maximum exhaust pressure	mbar	6x10 ⁻¹		4x10 ⁻²	
Recommended fore pump				2063 C2	
Maximum N ₂ flow rate	sccm	340	400	450	
Mounting orientation				Any	
Rotational speed	rpm			27 000	
Start-up time	min			2 min	
Water coil temperature	°C			65	
Maximum ambient temperature	°C			Pump 50°C / Controller 40°C	
Exhaust flange	ISO-KF			DN 40	
N ₂ purge flange	ISO-KF			DN 16	
Weight	kg (lb)	9 (19.8)	8.5 (18.7)	17.7 (39)	
Controller		ACT 600T ACT 250		ACT 1000T	
Controller weight	kg (lb)	4 (10.7) 1.8 (3.96)		8.5 (22.8)	
Controller size				1/2 Rack	
Power supply				100 to 240 V - 50/60 Hz - Single phase	
Maximum power consumption	VA	300		800	

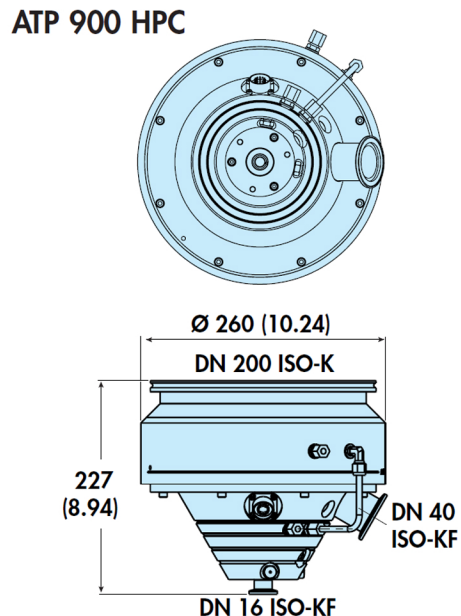
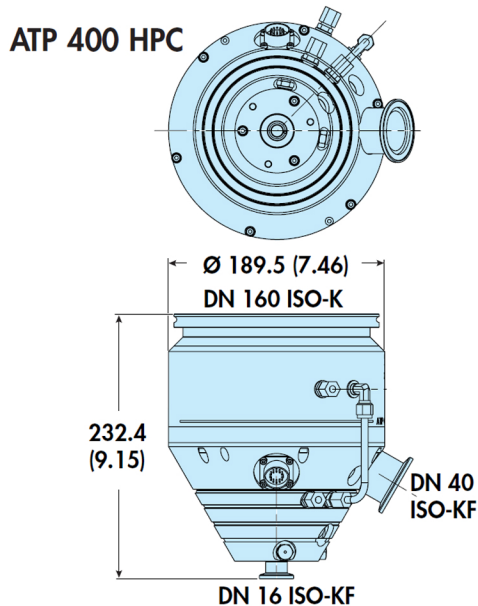
(1) Measured to Pneurop standards



Alcatel ATP-400HPC, 900HPC Pumping Curves



Dimensions





PROVAC

SALES

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Features & Benefits

- for high pressure corrosive applications
- low cost of ownership
- mounting in any orientation
- lubricated ceramic ball bearings
- low ultimate vacuum, rotational speed
- increased resistance to air inrush, gyroscopic effect & low ball bearing stress



Applications

- space simulation • thin film deposition • ion pump evacuation • UHV system • particles accelerator • ion source • surface analysis • mass spectrometer • scanning electron microscope • leak detection
- high pressure corrosive gas processes